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CROSS REFERENCE TO RELATED APPLICATION

B1

This application is a divisional of U.S. Pat. No. 6,335,288, filed August 24, 2000.

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Please amend the paragraph at p. 15, l. 25 – p. 16, l. 2 to read as follows:

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B2

An example of a system that may incorporate some or all of the subsystems and routines described above would be the ULTIMA™ system, manufactured by APPLIED MATERIALS, INC., of Santa Clara, California, configured to practice the present invention. Further details of such a system are disclosed in commonly assigned U.S. Patent No. 6,170,428, filed July 15, 1996, entitled "Symmetric Tunable Inductively-Coupled HDP-CVD Reactor," having Fred C. Redeker, Farhad Moghadam, Hirogi Hanawa, Tetsuya Ishikawa, Dan Maydan, Shijian Li, Brian Lue, Robert Steger, Yaxin Wang, Manus Wong and Ashok Sinha listed as co-inventors, the disclosure of which is incorporated herein by reference. The described system is for exemplary purpose only. It would be a matter of routine skill for a person of skill in the art to select an appropriate conventional substrate processing system and computer control system to implement the present invention.

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REMARKS

In the Office Action dated March 11, 2002 (paper no. 4), Claims 17 – 22 were rejected under 35 U.S.C. §103(a). These claim rejections are respectfully traversed. A copy of the claims pending is included in an Appendix.